



제25회 한국반도체학술대회

The 25th Korean Conference on Semiconductors

2018년 2월 5일(월)-7일(수), 강원도 하이원리조트 컨벤션 호텔

2018년 2월 6일(화), 14:10-15:55

Room K (육백II, 6층)

Q. Metrology, Inspection, and Yield Enhancement 분과

[TK2-Q] Nanoanalysis

좌장: 박주철 센터장(구미전자정보기술원), 양준모 박사(나노종합기술원)

TK2-Q-1 14:10-14:25	Dynamic Thin Film Thickness Measurement based on Snapshot Spectro-Ellipsometry Vamara Dembele ¹ , Inho Choi ¹ , Madhan Jayakumar Paul ¹ , Sukhyun Choi ¹ , Junho Kim ¹ , Won Chegal ² , and Daesuk Kim ¹ ¹ <i>Division of Mechanical System Engineering, Chonbuk National University,</i> ² <i>Advanced Instrumentation Institute, Korea Research Institute of Standards & Science</i>
TK2-Q-2 14:25-14:55	[초청] Strain-Engineering in Advanced CMOS Structures Dae-Hong Ko <i>Department of Materials Science and Engineering, Yonsei University</i>
TK2-Q-3 14:55-15:25	[초청] Applications of TEM Electron Energy-Loss Spectroscopy (EELS) Analysis for Materials in Semiconductor Devices Jucheol Park, Jeong Eun Chae, Ji-Soo Kim, SangYeol Nam, and Min-Soo Kim <i>Materials Characterization Center, Gumi Electronics & Information Technology</i>
TK2-Q-4 15:25-15:40	Wafer 표면 Roughness에 따른 Thermal Oxide 영향 연구 정성우, 박정길, 김자영, 강희복 <i>SK Siltron</i>
TK2-Q-5 15:40-15:55	Detection of Metal Contamination in the Layer of Silicon Wafers Seung-Ik Jo, Ji-Yeon Lim, Sung-wook Lee <i>SK Siltron</i>
TK2-Q-6 15:55-16:10	Development of Interatomic Potentials in Si-O-F Systems Changhoon Heo ¹ , Hae-won Choi ¹ , In-ki Jeong ² , and Young-gui Yoon ² ¹ <i>SEMES R&D Center,</i> ² <i>Department of Physics, Chung-Ang University</i>